

The ORS ARC

The ARC in-situ wafer bow sensor will significantly improve your yield and uniformity.

The ARC has been developed to help you to understand how wafer bow evolves during your process.

Accurate Measurement

The ARC not only measures spherical bow but more importantly non-spherical bow.

Multi Sensor Configuration

Flexible control software allows for multi sensor control and configuration. This enables easy alignment of wafer bow with reflectance and temperature measurements from the same wafer.

Fast data acquisition

Whether your stage rotates at 5 or 1500rpm, every wafer is monitored on each rotation of your main stage. The ARC offers the fastest data acquisition rate of any commercially available *in-situ* sensor.

Common interface

Ideally suited to any MOVPE reactor providing a common interface irrespective of reactor type or make. Compatible with Planetary™, Showerhead and Turbodisc™ reactors.

Quality

ORS is ISO 9001 accredited and the ARC sensor is fully CE marked.

Installation

Mounting solutions are available for all configurations. The small footprint means the minimum of space is needed on your reactor.



Benefits of the ARC

- Accurate to 0.3 μm^{-1} radius of curvature
- Quick and easy to install
- Also suitable for Arsenides and Phosphides
- Control of wafer bow significantly improves process performance
- Monitors across the whole wafer
- No focusing required
- High speed acquisition means compatible with susceptor speeds of 5 – 1500 rpm
- A common interface for multi-reactor type compatibility
- For large single wafers measurements can be made mid radius

Optical Reference Systems (ORS) Ltd.
 OpTIC Technium, St. Asaph Business Park,
 St. Asaph LL17 0JD. United Kingdom.
 T: +44 (0) 1745 535188
 F: +44 (0) 1745 535186
www.ors-ltd.com

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